



IFW

# TRANSMITTAL OF FORMAL DRAWINGS

Docket No.  
YOR920030526US1 (17107)

In the Application Of: Stephen W. Bedell, et al.

Application No.	Filing Date	Confirmation No.	Examiner	Customer No.	Group Art Unit
10/728,519	12/5/2003	Unassigned	Unassigned	23389	2818

Invention: **METHOD OF FABRICATING STRAINED Si SOI WAFERS**

Address to:  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Transmitted herewith are:

4 sheets of formal drawing(s) for this application.

☒ Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c).

*Signature*

Leslie S. Szivos, Ph.D.  
Registration No. 39,394

Dated: July 26, 2004

I certify that this document and attached formal drawings are being deposited on 7/26/2004 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Signature of Person Mailing Correspondence*

Leslie S. Szivos, Ph.D.

*Typed or Printed Name of Person Mailing Correspondence*